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# “Photoluminescence Investigation of Bulk GaAsBi on GaAs”

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# Outline

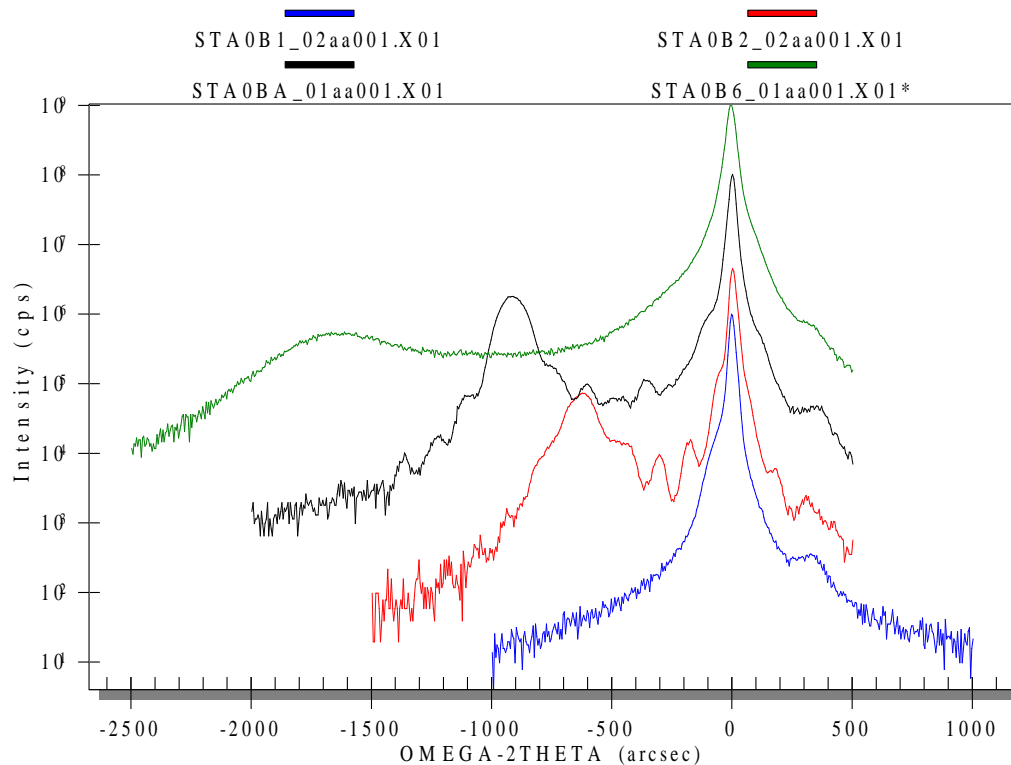
- Introduction
- Wafer Details
- GaAsBi HRXRD
- Power Dependent PL
- Temperature Dependent PL
- Room temperature FWHM
- Summary

# Introduction

- Bi-containing alloy for optoelectronics and spintronics devices.
- We want devices to be cheap, reliable, temperature insensitive etc.
- PL to assess GaAsBi quality.

- Omicron STM-MBE
- Wafer size: 3.5 x 5 mm
- Ga assisted oxide removal to avoid thick buffer.

Material	Thickness (nm)
GaAs cap	80
GaAs <sub>1-x</sub> Bi <sub>x</sub>	160
GaAs buffer	80
S.I or n+ (100) GaAs substrate	

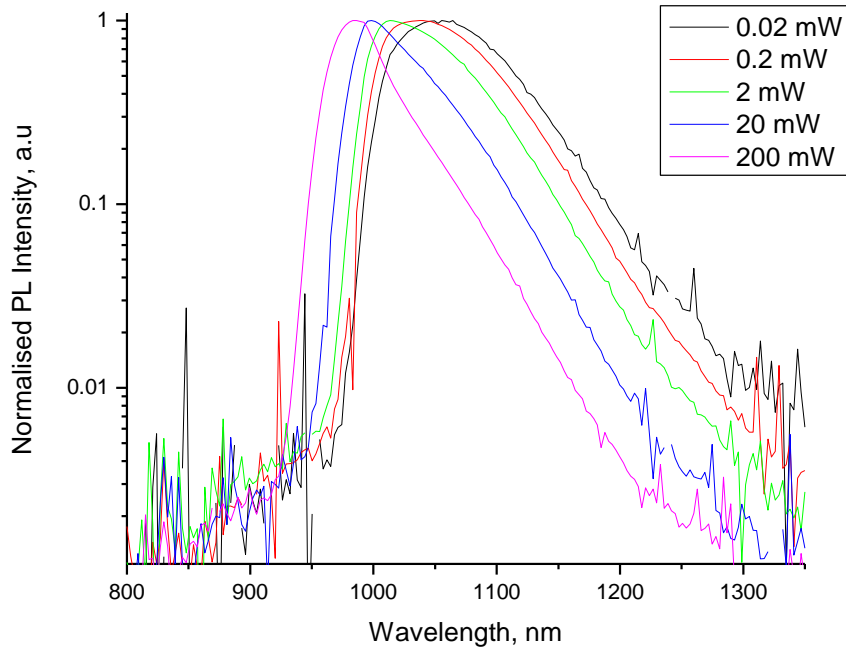


Sample	Bi content
B1	0
B2	0.022
BA	0.032
B6	0.058

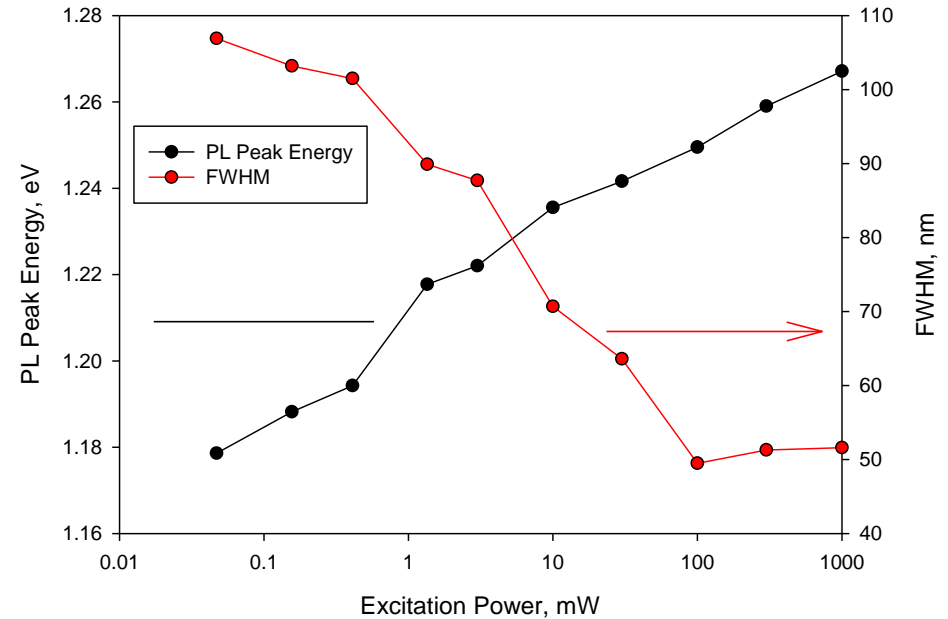
- $[Bi] = 0 - 0.058$
- Fringes clearly observed for  $[Bi] = 0.032$
- No traces of Bi on non-Bi wafers grown afterwards.

# Power dependent PL

Power Dependent PL at 10 K

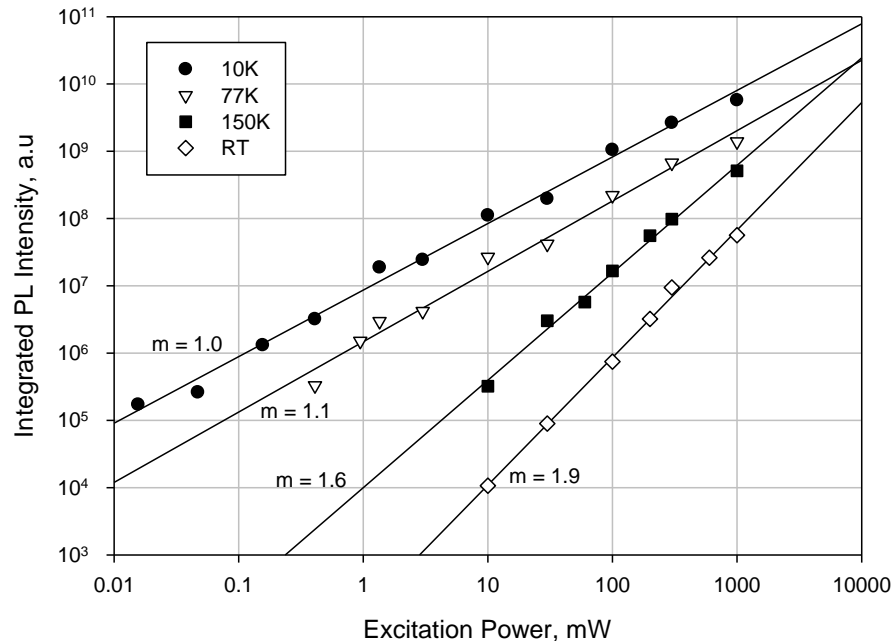


Power Dependent PL at 10 K

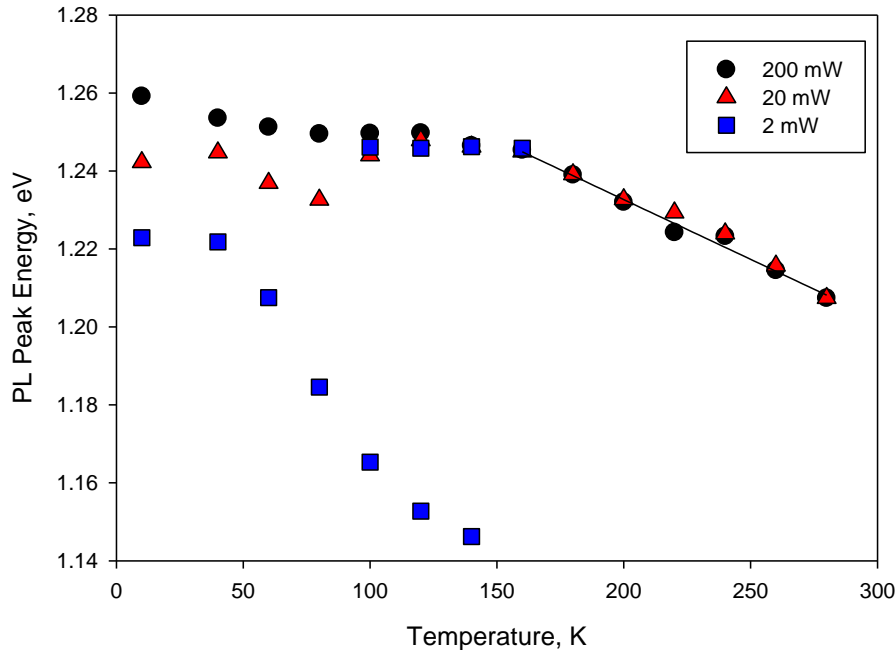


- At RT, PL peak energy is independent of the excitation power.
- PL peak energy is blue-shifted with increasing power at 10 K.
- FWHM reduces as power is increased at 10 K.

# Power dependent PL



- At 10 K, radiative recombination is dominant ( $m=1$ ).
- Non-radiative recombination dominated at RT ( $m\sim 2$ ).
- Mixture of both at intermediate temperatures ( $m=1-2$ ).



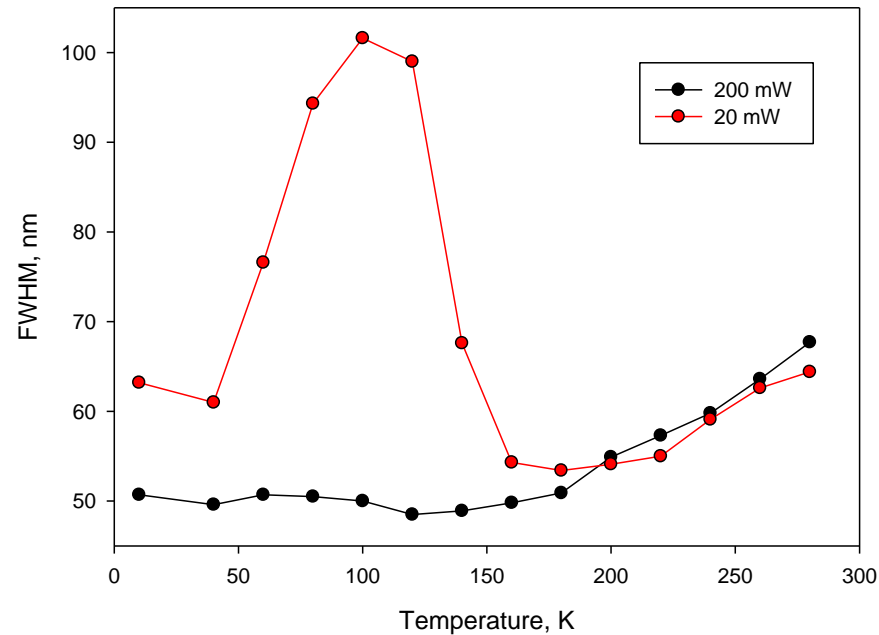
Source	Bi content	$a$ (meV/K)
GaAs	0	0.46
Pettinari <i>et al</i>	0.019	0.36
Sheffield BA	0.032	0.31
Imhof <i>et al</i>	0.04-0.05	0.27

- S-shape behaviour observed – localisation.
- Localisation potential = 15 meV.
- Expect  $a$  to decrease with increasing [Bi]. (GaNaNsBi; 0.15 meV/K, [Bi]=0.026).
- Origin of peak at 1.22 eV (10 K) is unknown.





# Temperature dependent FWHM



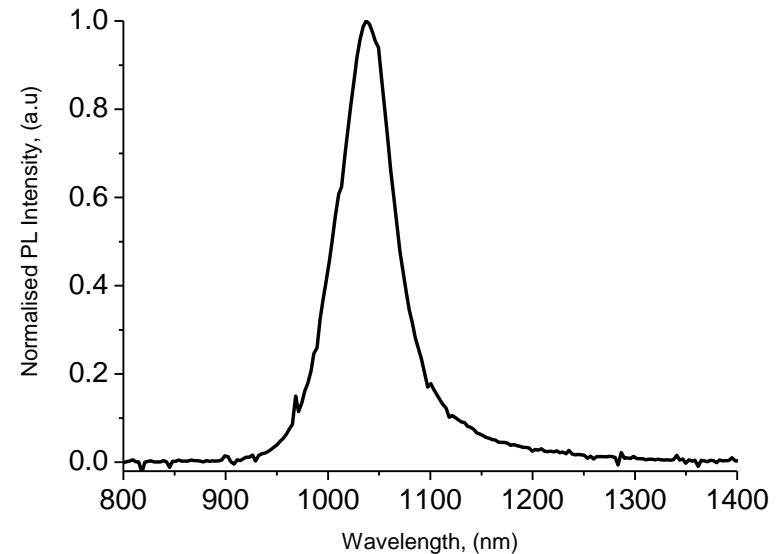
- FWHM maxima due to increase in exciton mobility.
- $kT@160\text{ K} = 14\text{ meV}$ . Consistent with localisation energy (15 meV).
- FWHM increase at  $T > 160\text{ K}$  due to thermal distributions and phonon scattering.



# Room Temperature FWHM

Source	Bi content (%)	FWHM (nm)	$\lambda_p$ (nm)
Tixier <i>et al</i> 2003	0.013	101	979
Lu <i>et al</i> 2009	0.014	85	-
Sheffield B2	0.022	69 (45@10K)	990
Lu <i>et al</i> 2009	0.023	107	1016
Bertulis <i>et al</i> 2006	0.029	195	1055
Tixier <i>et al</i> 2003	0.031	118.8	1078
Sheffield BA	0.032	65 (51@10K)	1038
Lu <i>et al</i> 2009	0.036	130	-

RT PL, P = 200 mW (600 W/cm<sup>2</sup>)



- FWHM of 65 nm (75 meV) > ~45 meV due to thermal distribution broadening. Wide FWHM is due to Bi fluctuations.
- Narrowest RT FWHM compared with reported values in literature.

# Conclusions

- HRXRD shows clear fringes for [Bi] up to 3.2%, indication of good interface.
- Radiative recombination is dominant at 10 K while non-radiative recombination dominated at RT. Mixture of both at intermediate temperatures.
- Evidence of localisation effects:
  - PL peak energy dependent on excitation power.
  - S-shape with localisation potential of 15 meV.
  - FWHM peaking at 100 K.
- $a = 0.31$  meV/K between  $150 \text{ K} < T < 280 \text{ K}$ .
- Demonstrated  $\text{GaAs}_{0.973}\text{Bi}_{0.032}$  with FWHM = 65 nm (75 meV) at RT. Possibility of growing high quality GaAsBi.



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1<sup>st</sup> International Workshop on Bismuth-Containing Semiconductors, Michigan, USA